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He started his MEMS research in 1983. His research areas covers wet anisotropic etching of silicon, mechanical properties of MEMS materials, and applied microsystems such as sensors and actuators. He co-chaired IEEE MEMS-workshop in 1979. He was the Editor in Asia of the Journal of Micromechanics and Microengineering (IOP). He is honorary member of the Japan Society of Mechanical Engineers (JSME) and of the Japan Society for Precision Engineering (JSPE). He is the founding chair of the Micro/Nano Science and Technology Division established in the JSME.